

**Notice of References Cited**

Application/Control No.

09/491,429

Applicant(s)/Patent Under

Reexamination

HEANUE ET AL.

Examiner

Armando Rodriguez

Art Unit

2828

Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6018535	01-2000	Maeda	372-20
	B	US-5771252	06-1998	Lang et al	372-20
	C	US-2001/0036206	11-2001	Jerman et al	372-20
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Akimoto et al, Micro electro mechanical systems (MEMS) and their photonic application, SPIE Proceedings, vol. 3098, September 1997, pp. 374-381.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.